(408) 947-8200

Blakely, Sokoloff, Taylor & Zafman LLP (408) 947-8. Title: Raster Frame Beam System For Electron Beam Lithography 1st Named Inventor: Meir Aloni Express Mail No.: EV301791312US Docket No.: 6317P

Sheet: 1 of 10

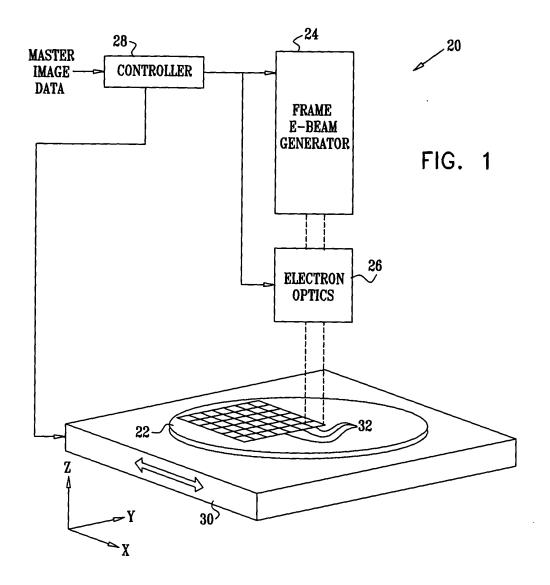
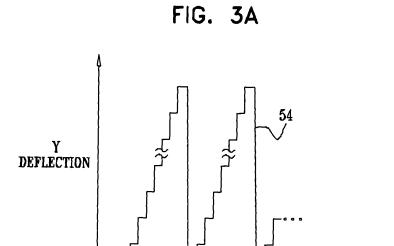
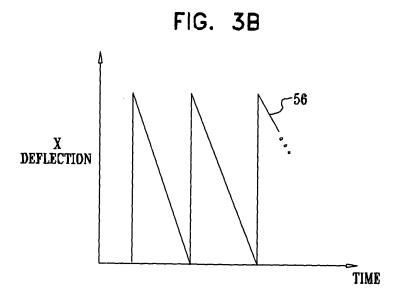


FIG. 2 Y 46 2N 42 N+3 X

TIME





Blakely, Sokoloff, Taylor & Zafman LLP (408) 947-8200
Title: Raster Frame Beam System For Electron Beam Lithography
1st Named Inventor: Meir Aloni
Express Mail No.: EV301791312US
Docket No.: 6317P013

Sheet: 3 of 10

FIG. 4A

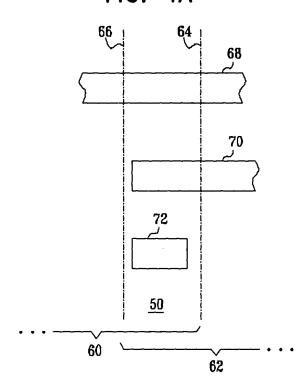
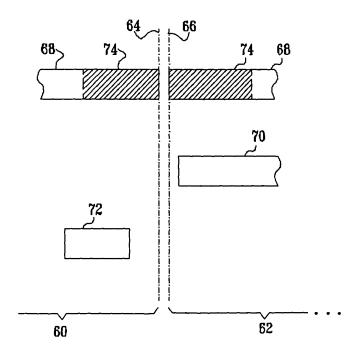


FIG. 4B

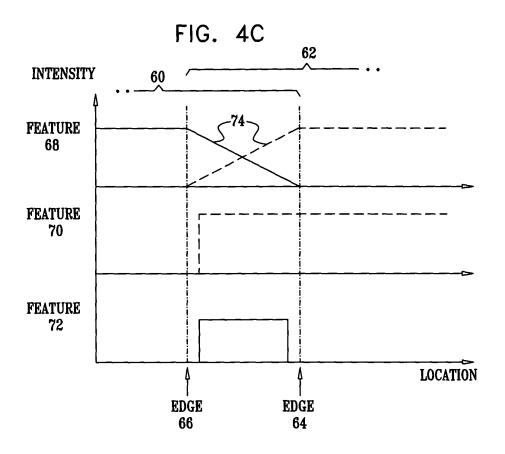


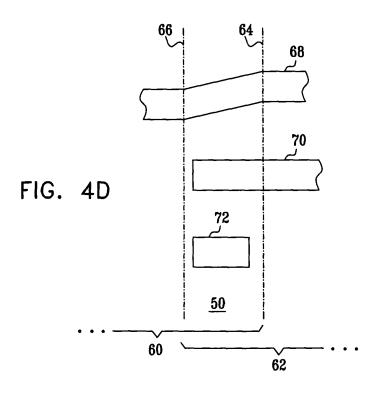
Blakely, Sokoloff, Taylor & Zafman LLP (408) 947-8 Title: Raster Frame Beam System For Electron Beam Lithography

(408) 947-8200

1st Named Inventor: Meir Aloni Express Mail No.: EV301791312US

Sheet: 4 of 10



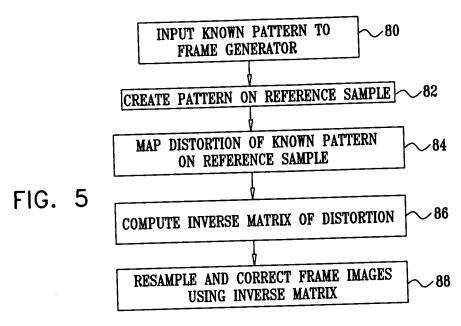


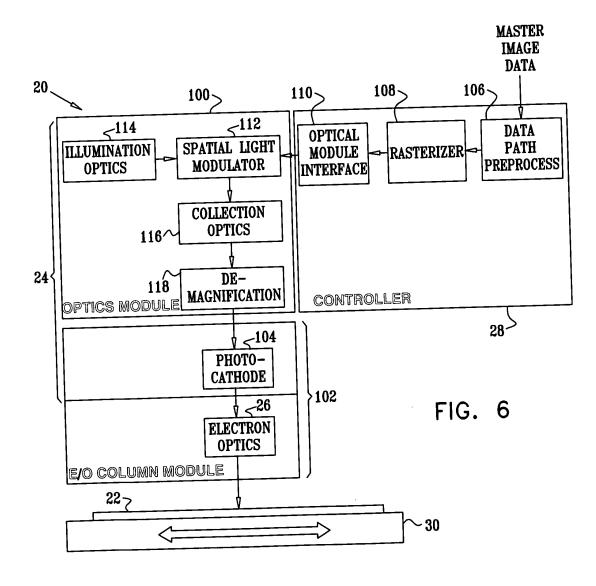
Blakely, Sokoloff, Taylor & Zafman LLP (408) 947-8200 Title: Raster Frame Beam System For Electron Beam Lithography

1st Named Inventor: Meir Aloni

Express Mail No.: EV301791312US

Sheet: 5 of 10

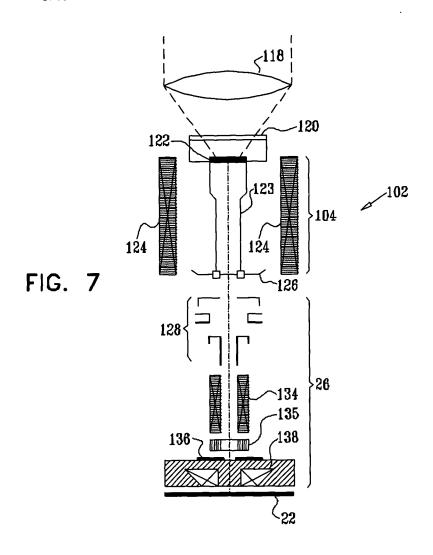


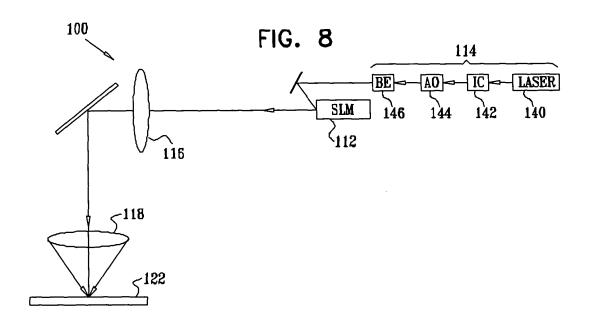


Blakely, Sokoloff, Taylor & Zafman LLP (408) 947-8
Title: Raster Frame Beam System For Electron Beam Lithography
1st Named Inventor: Meir Aloni (408) 947-8200

Express Mail No.: EV301791312US

Sheet: 6 of 10

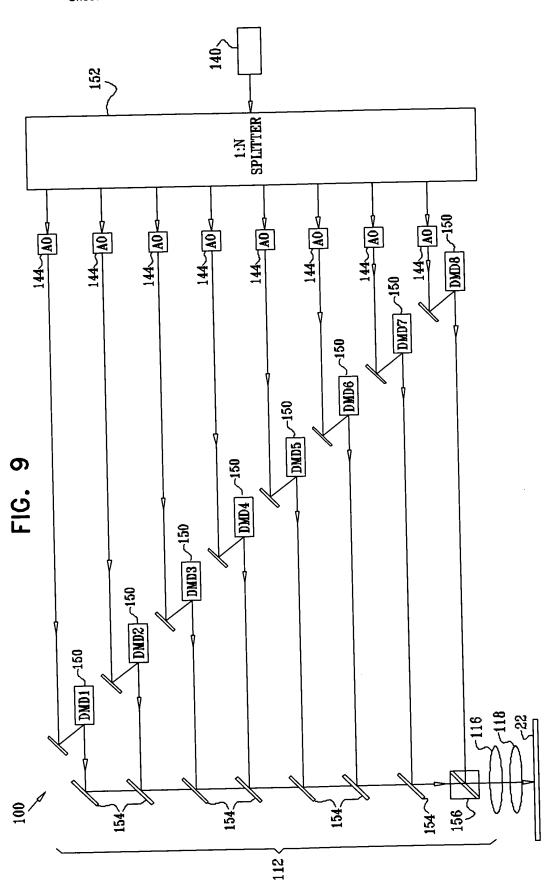




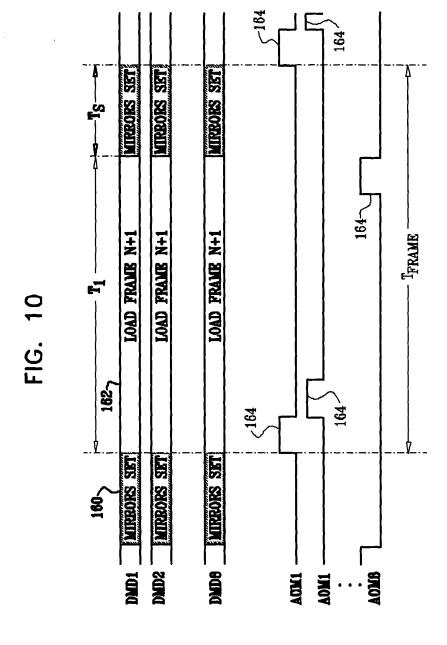
Blakely, Sokoloff, Taylor & Zafman LLP (408) 947-8200
Title: Raster Frame Beam System For Electron Beam Lithography
1st Named Inventor: Meir Aloni
Express Mail No.: EV301791312US

Shoet: 7 of 10

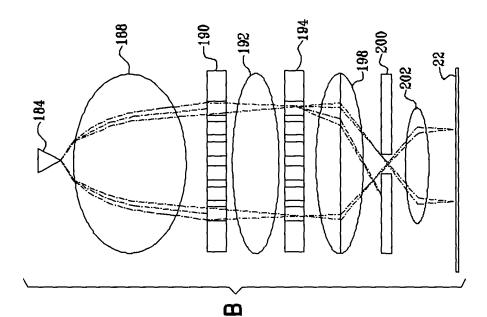
Sheet: 7 of 10

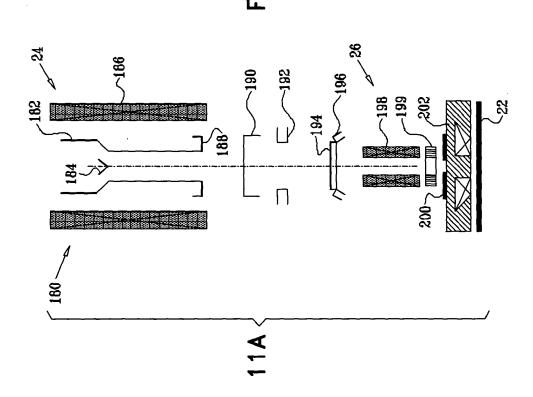


Blakely, Sokoloff, Taylor & Zafman LLP (408) 947-8200 Title: Raster Frame Beam System For Electron Beam Lithography 1st Named Inventor: Meir Aloni Express Mail No.: EV301791312US Docket No.: 6317P013 Sheet: 8 of 10



Blakely, Sokoloff, Taylor & Zafman LLP (408) 947-87. Title: Raster Frame Beam System For Electron Beam Lithography 1st Named Inventor: Meir Aloni Express Mail No.: EV301791312US Docket No.: 6317P0 Sheet: 9 of 10 (408) 947-8200





Blakely, Sokoloff, Taylor & Zafman LLP (408) 947-8200
Title: Raster Frame Beam System For Electron Beam Lithography

1st Named Inventor: Meir Aloni Express Mail No.: EV301791312US

Sheet: 10 of 10

FIG. 12A

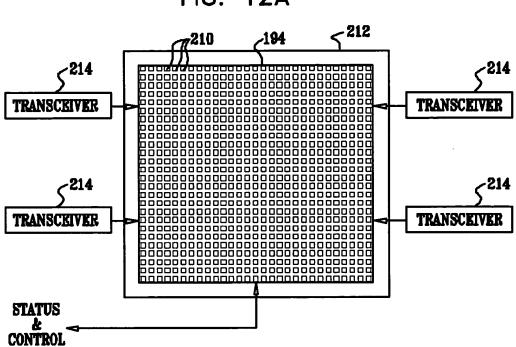


FIG. 12B

